



Contact Angle Analyzer

FPD (Flat Panel Display) CTA Series

The SEO CTA Series (FPD Contact Angle Analyzer) have been specifically developed to enable the evaluation of surface cleanliness and treatment conditions of large size samples (LCD displays, semiconductor Wafers, PDP, EL, and many others), and now it can be characterized without any difficulty.

Discover the difference that SEO can make for you. We have combined a very precise Contact Angle measurement with flexible sample handling by using the powerful optical system and the auto mapping dispensing system. that would allow you to analyze and evaluate the surface of any large samples up to 2000 x 2200 mm by just one click.



Wafer Pioneer Series

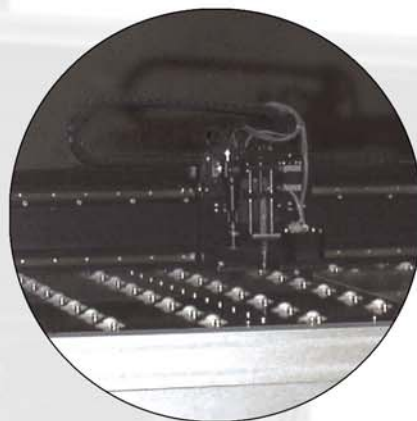
The Pioneer 300 Wafer Surface Analysis System is specially designed for use in 300 mm semiconductor wafer processing for quality control. The Pioneer 300 provides quick and accurate contact angle / surface energy measurements of the wafer surface to adhesion, cleanliness and surface treatments.

The position of the optic assembly is computer-controlled to allow for wafer surface mapping and can be precisely adjusted along the x-, y-, or z- axis. The use of the rotation stage inside makes this system well suited for semiconductor wafer applications and the closed sample stage prevents the samples from being contaminated by any organic particles. That insures the system could be used to monitor the ultra clean surface processing of silicon wafers.



Features

- Fully automated image analysis & calculation by computer.
- Simple and fast operation. Individual measurements on different regions of the sample can be made quickly and easily.
- Evaluation of your Surface Treatment and Cleaning process.
- Auto mapping display for Large size FPD (Flat Panel Display) & Wafer (8", 12").
- Available to modify the sample stage size according to specific applications.
- Contact Angle & Surface Energy.
- 2D and 3D surface analysis.



Application

- Measurement of contact angles and surface energies of FPD / Wafers.
- Evaluation of Cleanliness process.
- Coating assessment of the HMDS process.
- Adhesive and primer preparation.
- Coating uniformity & Coating quality.



Technical Data

Model	Pioneer 300	CTA series
• Max. Sample size (L x W)	300 mm Wafer (6" / 8" / 12" wafer available)	480 (L) ~ 2000 by 370 (W) ~ 2500 (mm)
• Max. Sample thickness	10 (mm)	60 (mm)
• Zoom	6.4 fold	6.4 fold
• Focus	Internal, ± 6 mm	Internal, ± 6 mm
• Resolution	768 x 576 NTSC, 16M color	768 x 576 NTSC, 16M color
• Moving type	Auto mapping & Manual control (X-, Y-, Z- and Rotating)	Auto mapping & Manual control
• Dispenser type	Automatic syringe system	Automatic syringe system
• Light source	White LED Module	White LED Module
• Contact Angle	5 ~ 180°, ± 0.1° accuracy	5 ~ 180°, ± 0.1° accuracy
• Evaluation Methods	Contact Angle / Surface Energy	Contact Angle / Surface Energy
• Operating system	Windows XP / 2000	Windows XP / 2000
• Power supply	110 to 240 VAC	110 to 240 VAC

SEO reserve the right to change specifications without notice



www.s-eo.com

SEO (Surface Electro Optics)

#946, Kosekdong, Suwon City,
Kyunggido, 441-813, Korea

Phone : +82.31.298.9561
Fax : +82.31.298.9565
E-mail : info@s-eo.com

Europe:
THASS Thermal Analysis & Surface Solutions GmbH
Pfungstweide 21
61169 Friedberg - Germany

Phone: +49-6031-16223-1
Fax: +49-6031-16223-29
E-mail: info@thass.net
Web: <http://thass.net>